

## Special Issue

# Piezoelectric MEMS/NEMS— Materials, Devices, and Applications, Third Edition

### Message from the Guest Editor

Piezoelectric materials have been playing a crucial role in a large number of devices and applications that have promoted a variety of today's technological progress and impacted modern society. They are widely used as sensors and actuators, and they can be deposited as thin films over standard silicon substrates or flexible substrates. The appeal of piezoelectric materials for MEMS/NEMS has been constantly growing, in particular, with the increasing commercial success of piezoelectric MEMS/NEMS devices. The upcoming era of Big Data, sensors, the Internet of Things (IoT), and Artificial Intelligence (AI) has been offering new opportunities and challenges to piezoelectric MEMS/NEMS devices, and we are seeing researchers throughout the world actively tapping into the state-of-the-art micro/nano-fabrication process, promoting advanced integration techniques, and exploring innovative applications to unleash the potential of piezoelectric MEMS/NEMS devices. In this Special Issue, we invite submissions exploring the latest advances in the field of piezoelectric MEMS/NEMS devices.

---

### Guest Editor

Dr. Wei Li

Department of Mechanical Engineering, College of Engineering and Mathematical Sciences, University of Vermont, Burlington, VT 05405, USA

---

### Deadline for manuscript submissions

30 June 2026



## Micromachines

---

an Open Access Journal  
by MDPI

---

Impact Factor 3.0  
CiteScore 6.0  
Indexed in PubMed



[mdpi.com/si/204346](https://mdpi.com/si/204346)

*Micromachines*  
Editorial Office  
MDPI, Grosspeteranlage 5  
4052 Basel, Switzerland  
Tel: +41 61 683 77 34  
[micromachines@mdpi.com](mailto:micromachines@mdpi.com)

[mdpi.com/journal/  
micromachines](https://mdpi.com/journal/micromachines)





# Micromachines

---

an Open Access Journal  
by MDPI

---

Impact Factor 3.0  
CiteScore 6.0  
Indexed in PubMed



[mdpi.com/journal/  
micromachines](https://mdpi.com/journal/micromachines)



## About the Journal

### Message from the Editor-in-Chief

You are invited to contribute research articles or comprehensive reviews for consideration and publication in *Micromachines* (ISSN 2072-666X). *Micromachines* is published in the open access format. Research articles, reviews and other contents are released on the internet immediately after acceptance. The scientific community and the general public have unlimited free access to the content as soon as it is published. As an open access journal, *Micromachines* is supported by the authors or their institutes by payment of article processing charges (APC) for accepted papers. We are pleased to welcome you as our authors.

---

### Author Benefits

#### High Visibility:

indexed within Scopus, SCIE (Web of Science), PubMed, PMC, Ei Compendex, dblp, and other databases.

#### Journal Rank:

JCR - Q2 (Instruments and Instrumentation) / CiteScore - Q1 (Mechanical Engineering)

#### Rapid Publication:

manuscripts are peer-reviewed and a first decision is provided to authors approximately 16.8 days after submission; acceptance to publication is undertaken in 1.9 days (median values for papers published in this journal in the second half of 2025).